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6/15/02 2823  
Serial No. 09/843,023  
Attorney Docket No. 40013.002

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Patent Application:  
Becky Losee

Serial No.: 09/843,023

Filed: April 26, 2001

For: METHODS FOR ETCHING SILICON  
TRENCHES

Confirmation No. 7229

Group Art Unit: 2823

Examiner: J. Muldonado

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TECHNOLOGY CENTER 2800

Commissioner for Patents  
Washington, D.C. 20231

Box Non-Final Response

Sir:

**RESPONSE TO RESTRICTION REQUIREMENT**

In response to the Office Action dated May 3, 2002, Applicant requests reconsideration of the restriction requirement and examination of all claims in light of the following remarks.

Remarks

The Office has required restriction to one of the following groups of inventions under 35 U.S.C. § 121:

Group I: claims 1-30, drawn to a method to form a semiconductor device, classified in class 438, subclass 709; and

I hereby certify that this correspondence is being deposited with the United States Postal Service as First Class Mail in an envelope addressed to:  
Assistant Commissioner for Patents, Washington, D. C. 20231, on this 16<sup>th</sup>  
Day of May 2002.

Signed: Emily L. Foley  
Dated: May 16, 2002